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**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q87267

Masahiko HATA

Appln. No.: 10/530,562

Group Art Unit: 1722

Confirmation No.: 8996

Examiner: Felisa Carla HITESHEW

Filed: April 7, 2005

For: METHOD FOR PRODUCING THIN FILM CRYSTAL WAFER, SEMICONDUCTOR  
DEVICE USING THE SAME AND METHOD FOR PRODUCING THE  
SEMICONDUCTOR DEVICE

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of  
three months, extending the time for responding to the Office Action of May 2, 2007 to  
November 2, 2007.

The statutory fee of \$1,050.00 is being charged to Deposit Account No. 19-4880 via EFS  
Payment Screen. The USPTO is also directed and authorized to charge all required fees, except  
for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit  
any overpayments to said Deposit Account.

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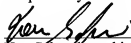
WASHINGTON OFFICE

**23373**

CUSTOMER NUMBER

Date: October 31, 2007

Respectfully submitted,



Ken Sakumabayashi  
Registration No. 58,490